

Thickness mapping and layer number identification of exfoliated van der Waals materials by Fourier imaging micro-ellipsometry

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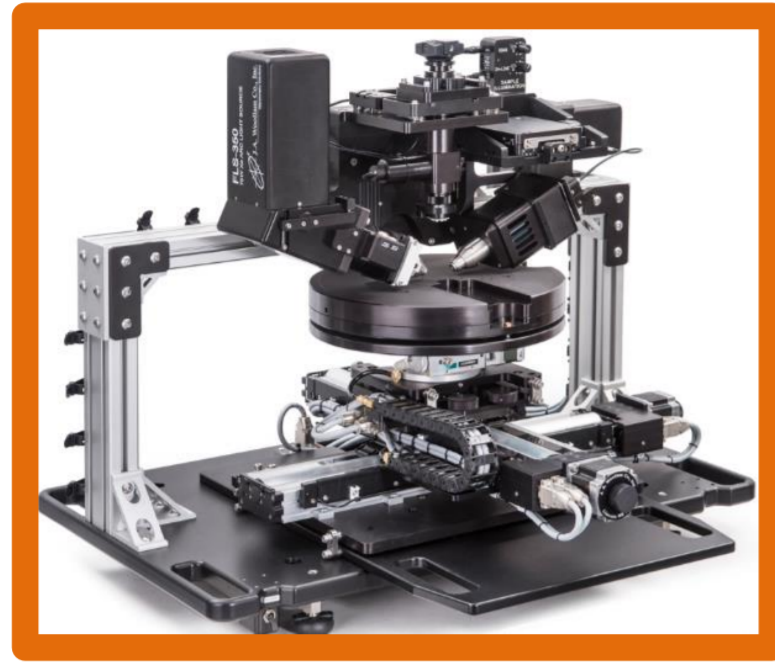
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1) Spectroscopic Ellipsometry

- Optical technique for thin film characterization
 - Complex refractive index (n and k)
 - Thin film thickness (sub-angstrom accuracy)

High lateral resolution Spectroscopic Ellipsometers (SEs)



Focused-beam SE



Imaging SE

Lateral Resolution

Tens-of- μm

Low

A few μm

High

Acquisition per measurement

Broadband, SINGLE angle

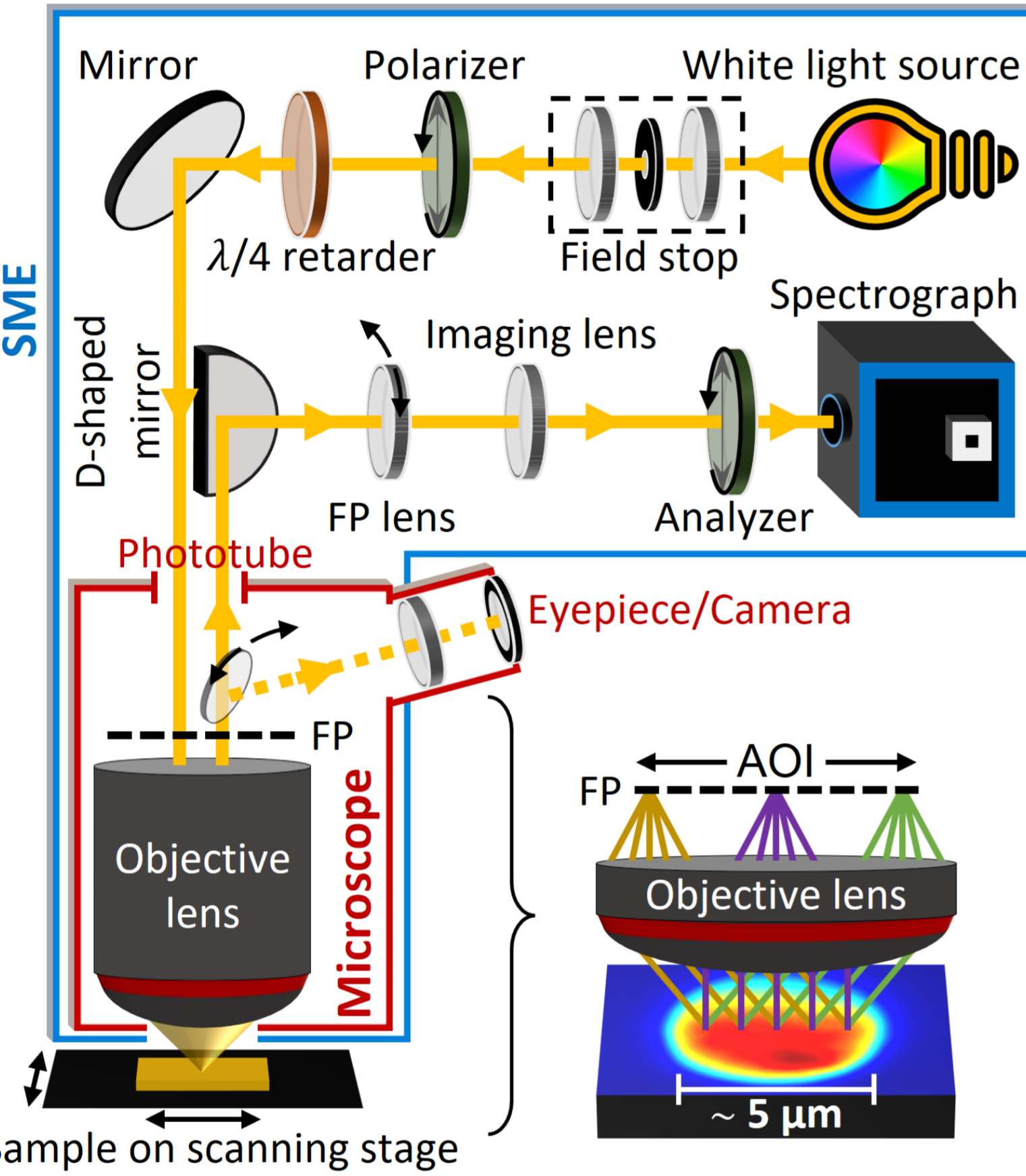
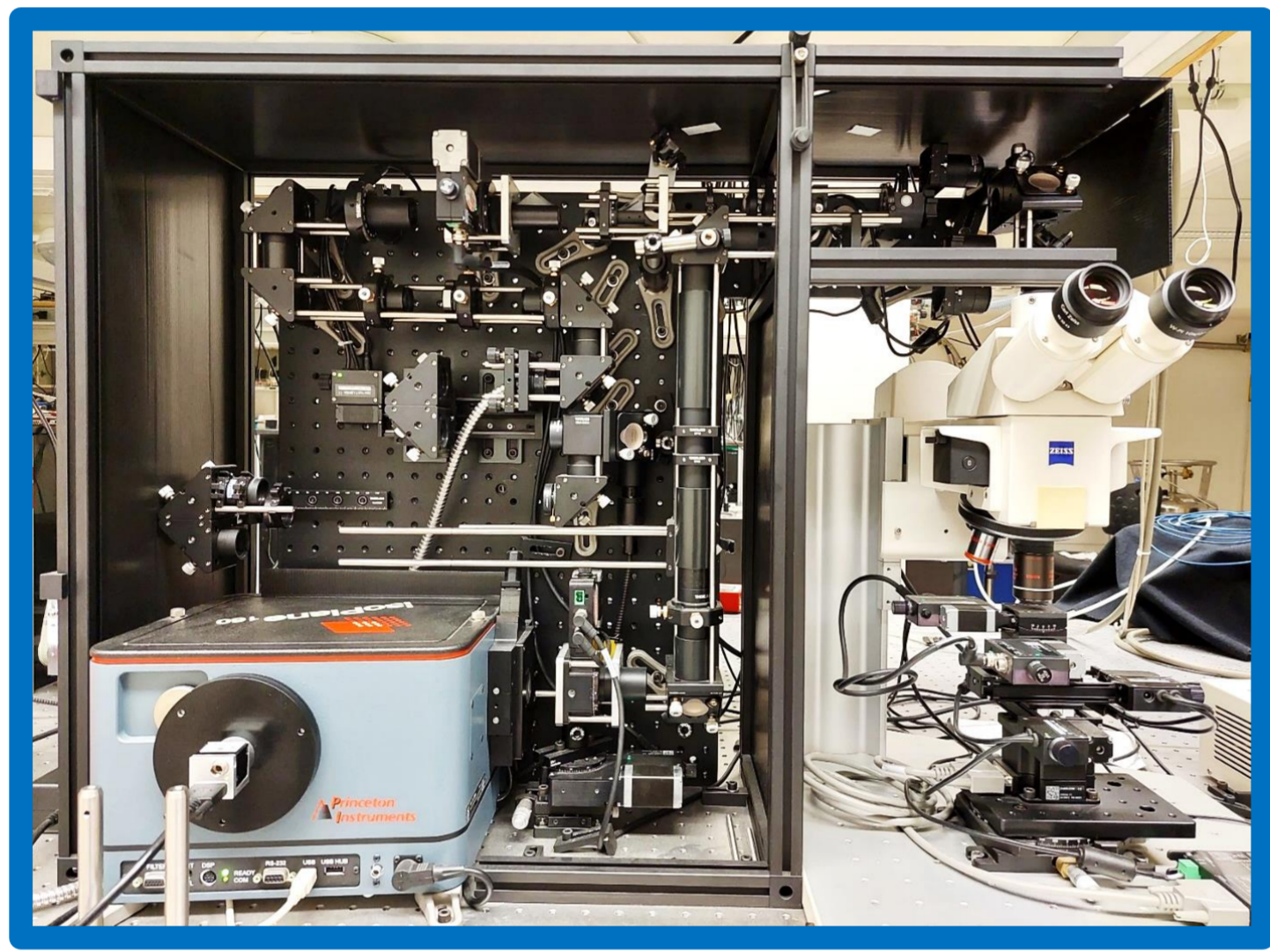
Low

SINGLE λ , SINGLE angle

Very low

Challenging to measure micro-structures

2) Spectroscopic Micro-Ellipsometer (SME)



- Patented technology [1]
- Proven accuracy [2]
- Microscope-integrable
- Fourier-plane imaging

High lateral resolution

A few μm

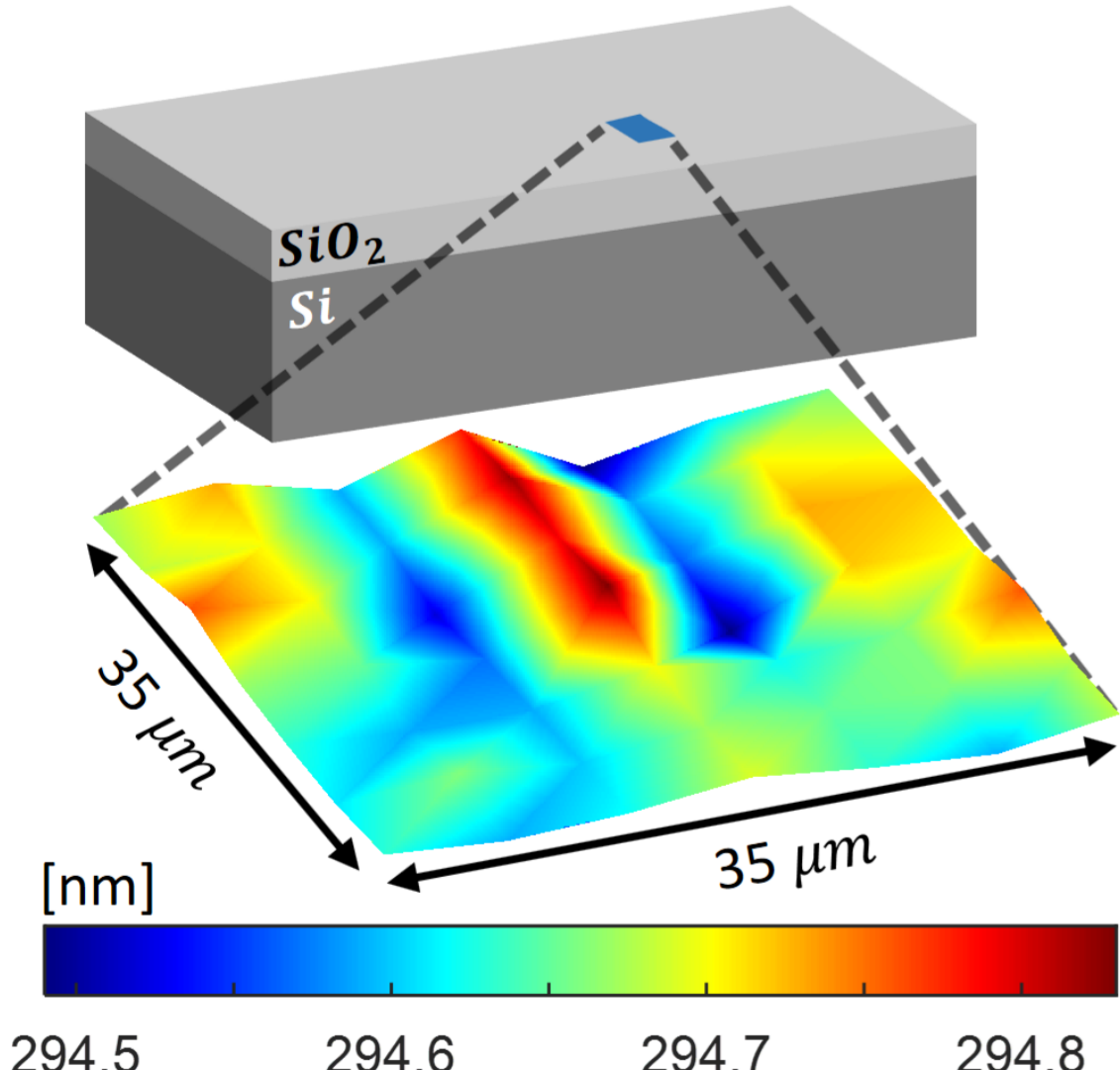
Down to 2 μm

Record high acquisition per measurement

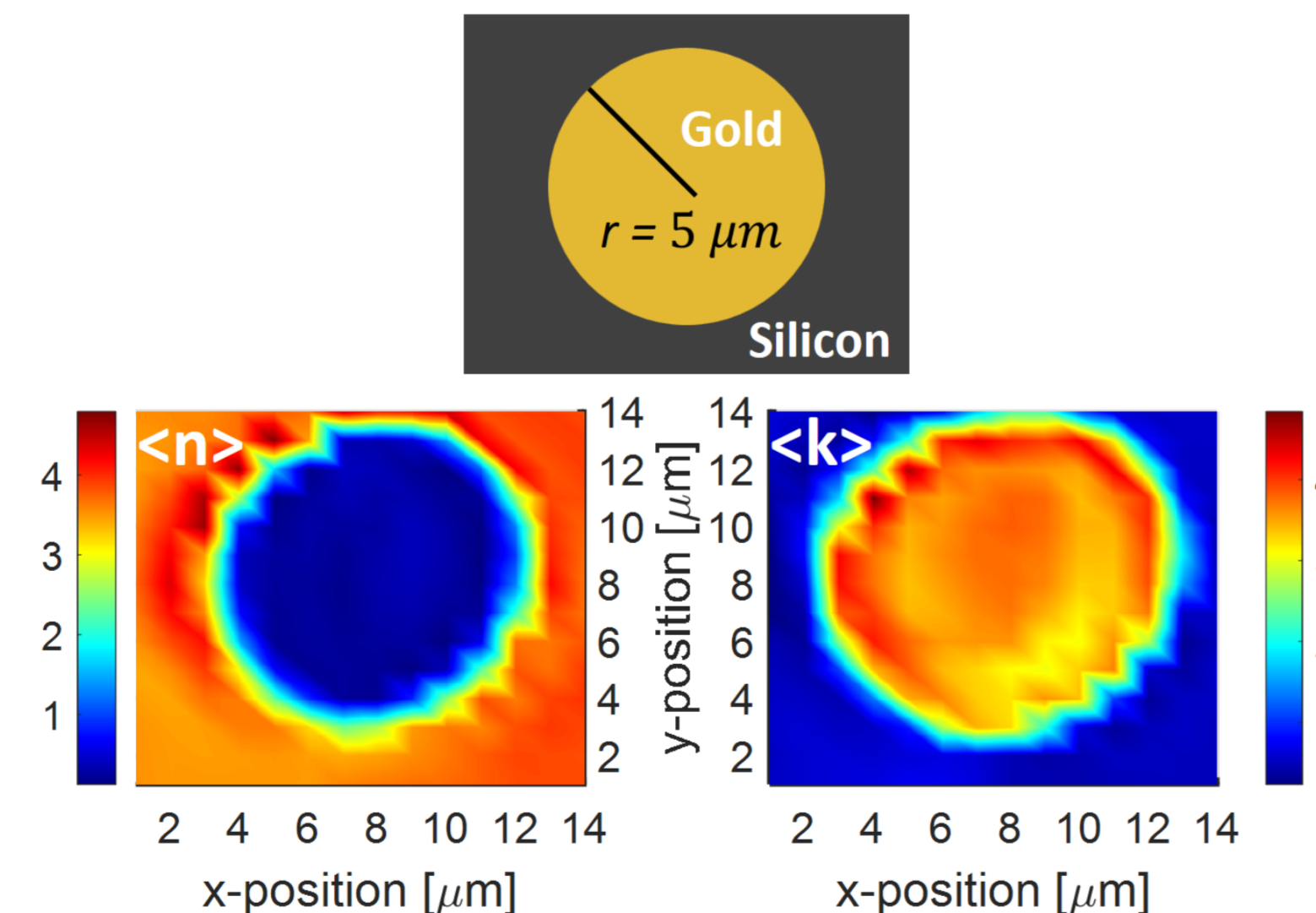
Broadband, MULTIPLE angles

High lateral resolution mappings

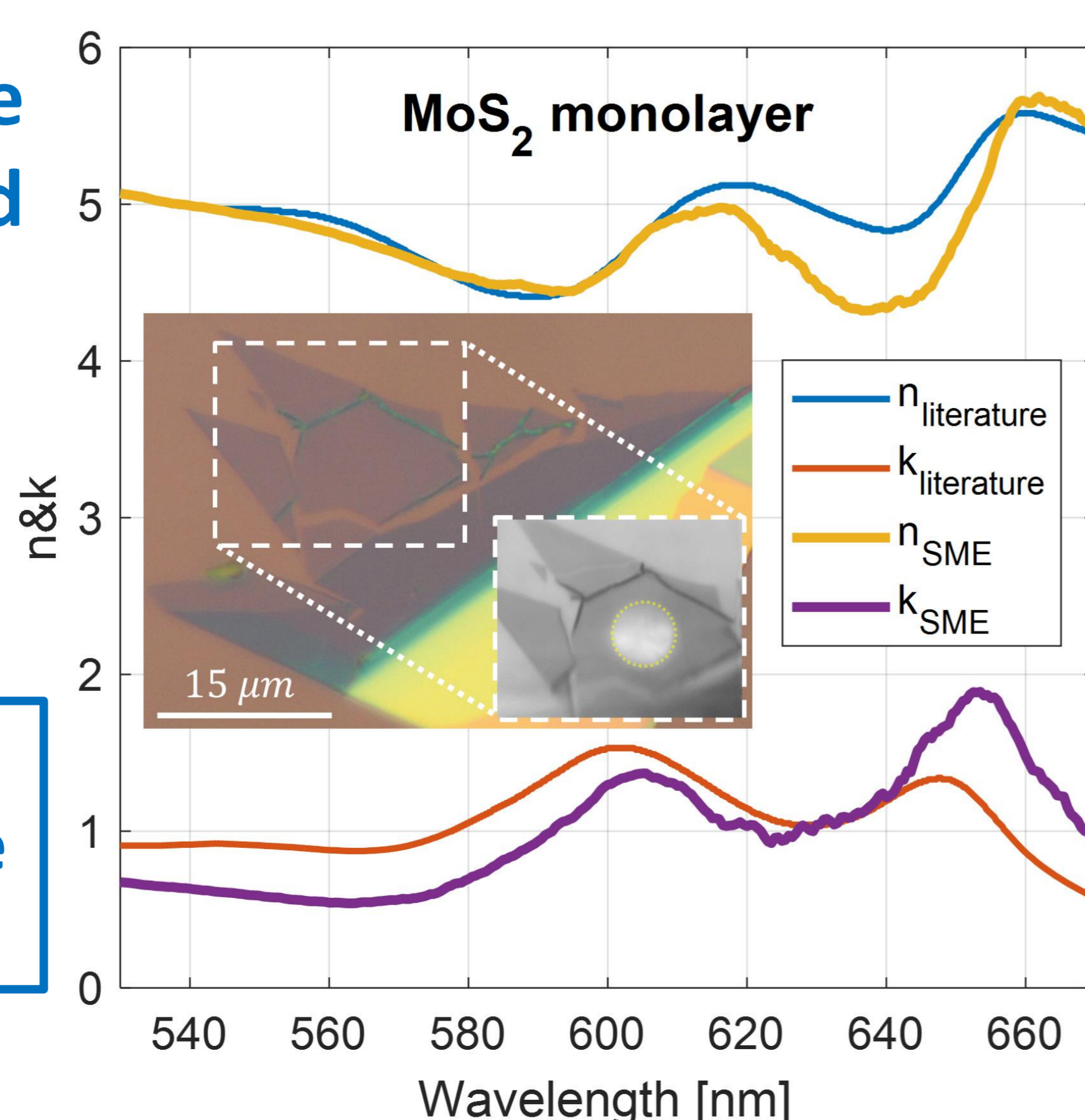
SiO₂ thickness mapping



Pseudo complex refractive index mapping



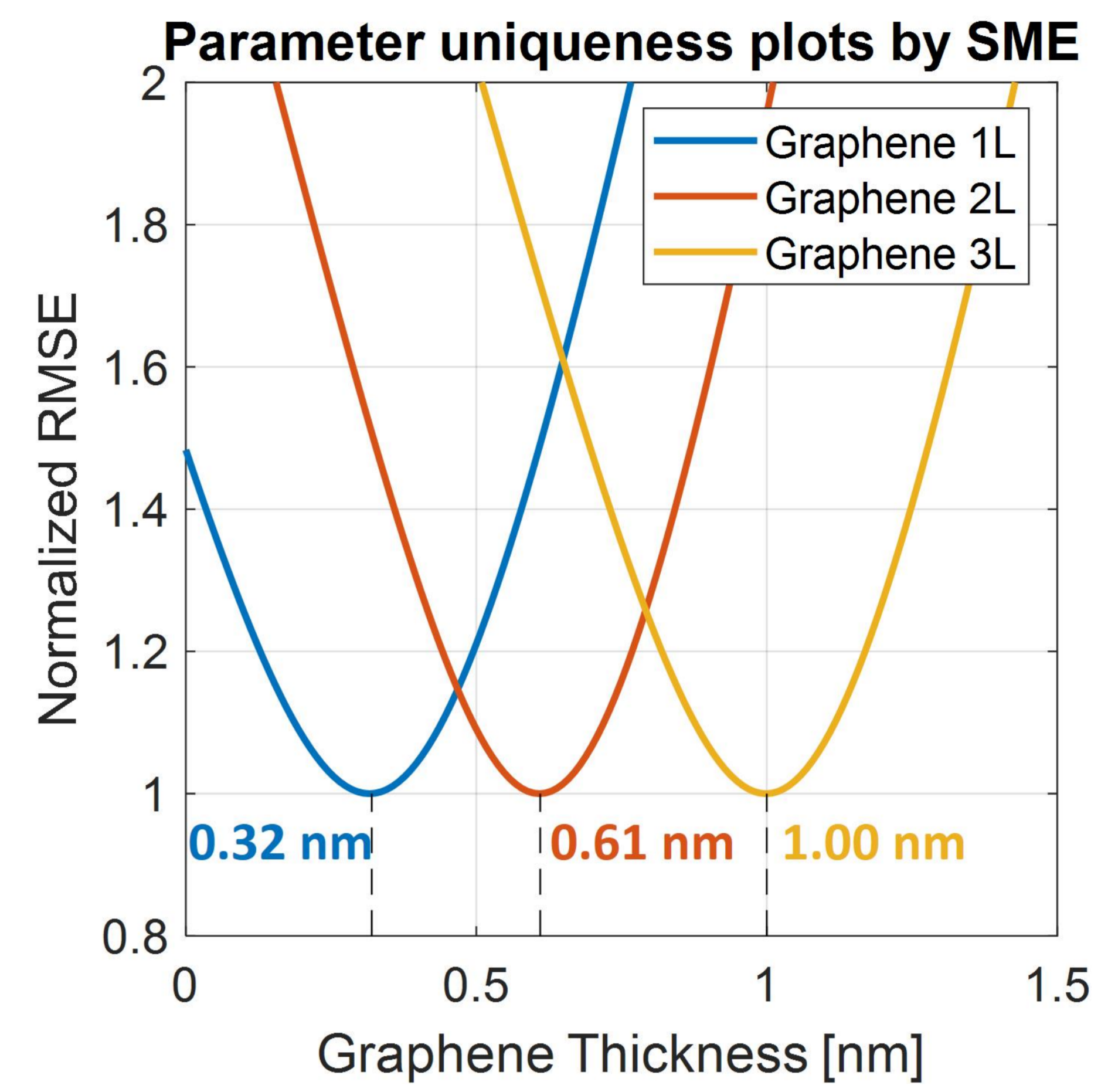
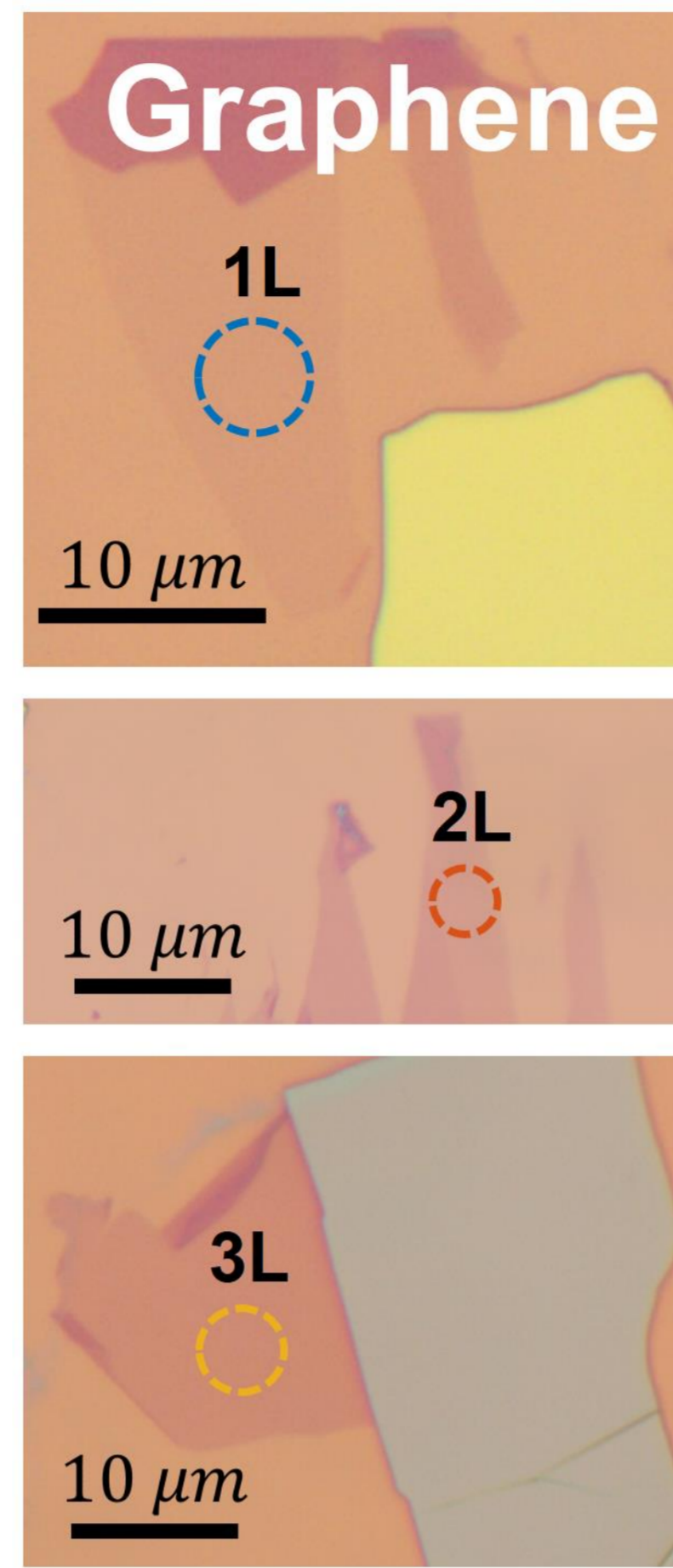
Complex refractive index of exfoliated MoS₂ monolayer



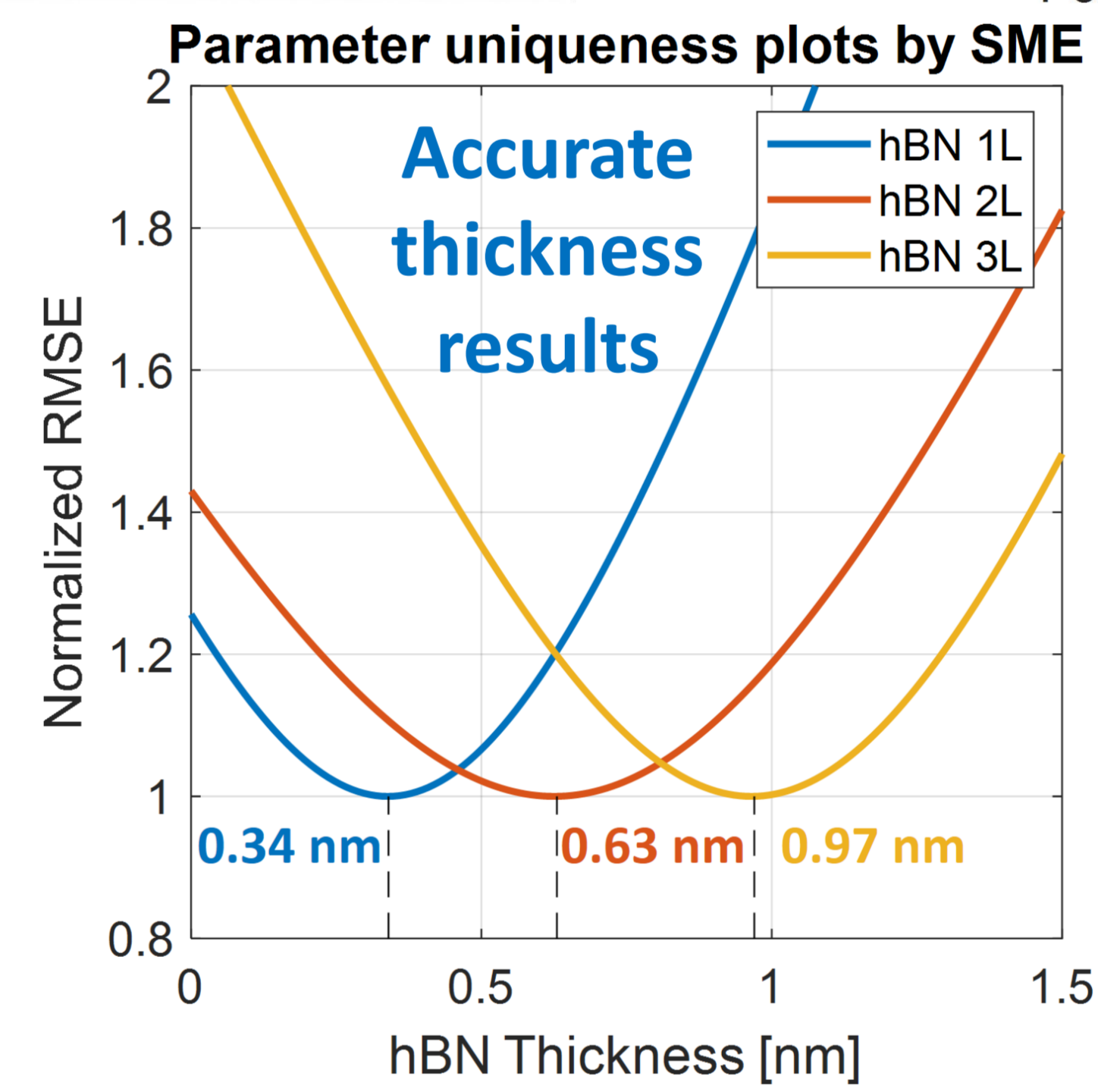
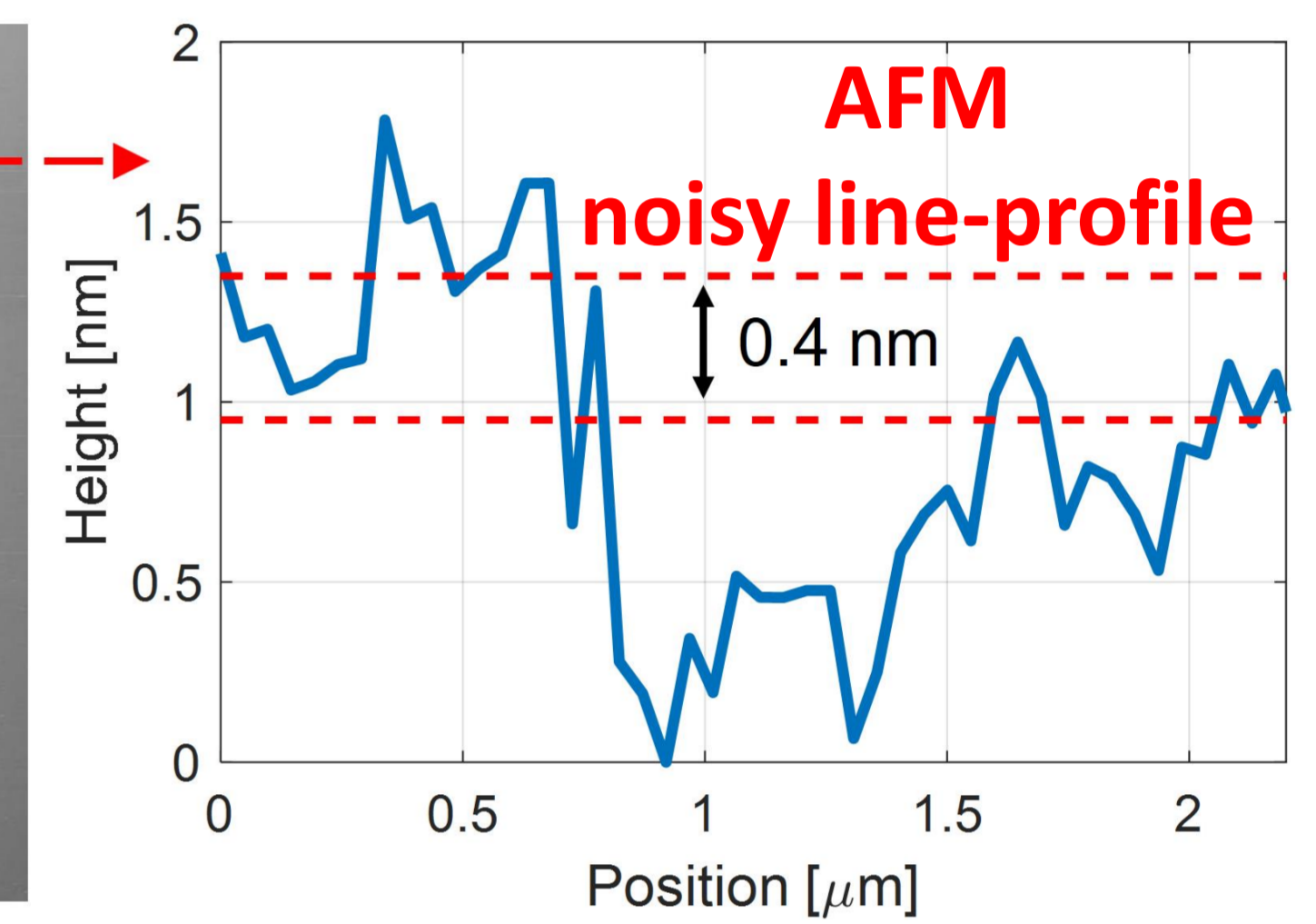
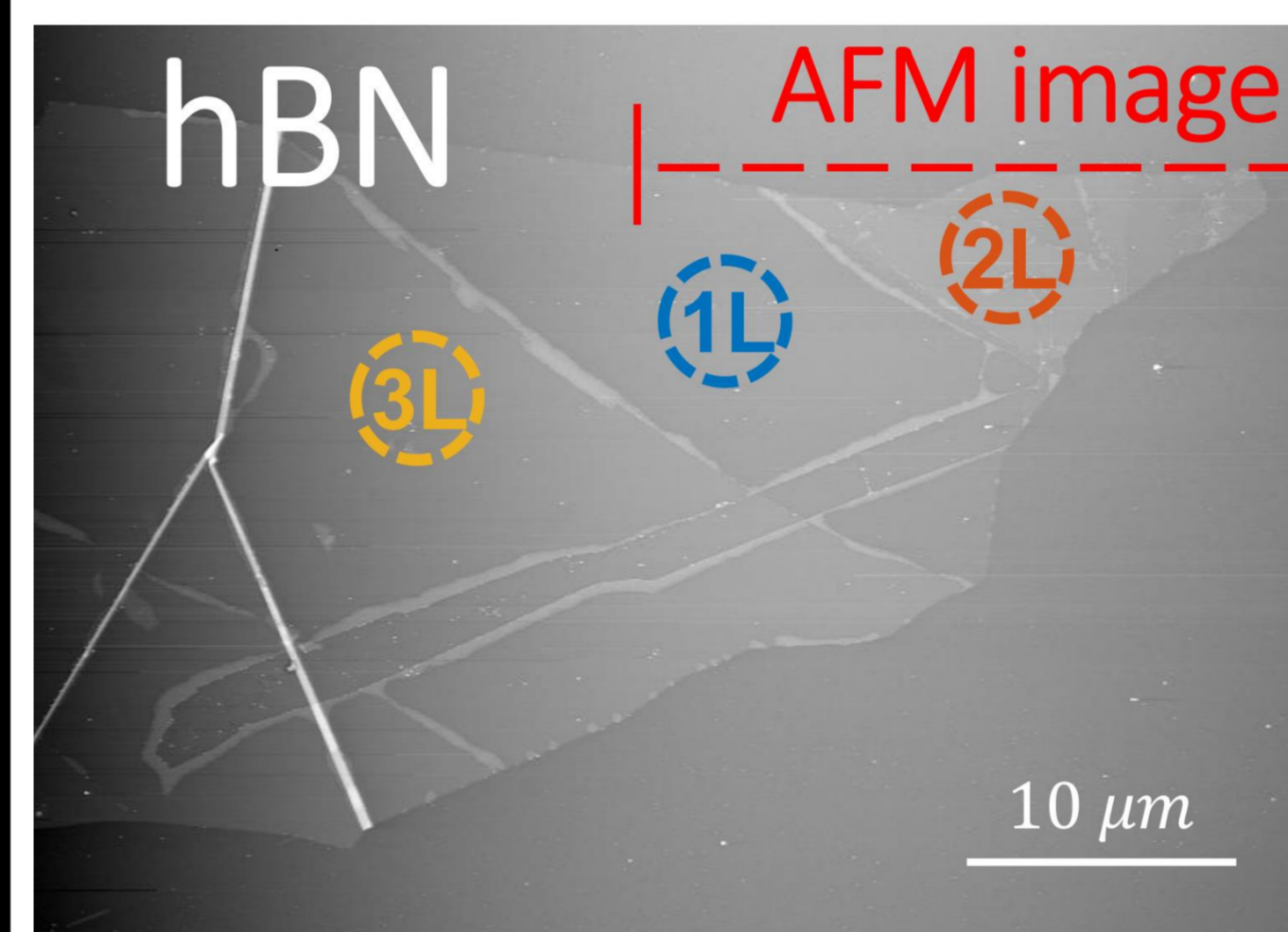
SME can easily and accurately measure micro-structures

3) Thickness of exfoliated vdW materials [3]

- Parameter uniqueness plot: Error between SME data and model, when the model is scanned for flake's thickness



Thickness of near-transparent hBN flakes by SME



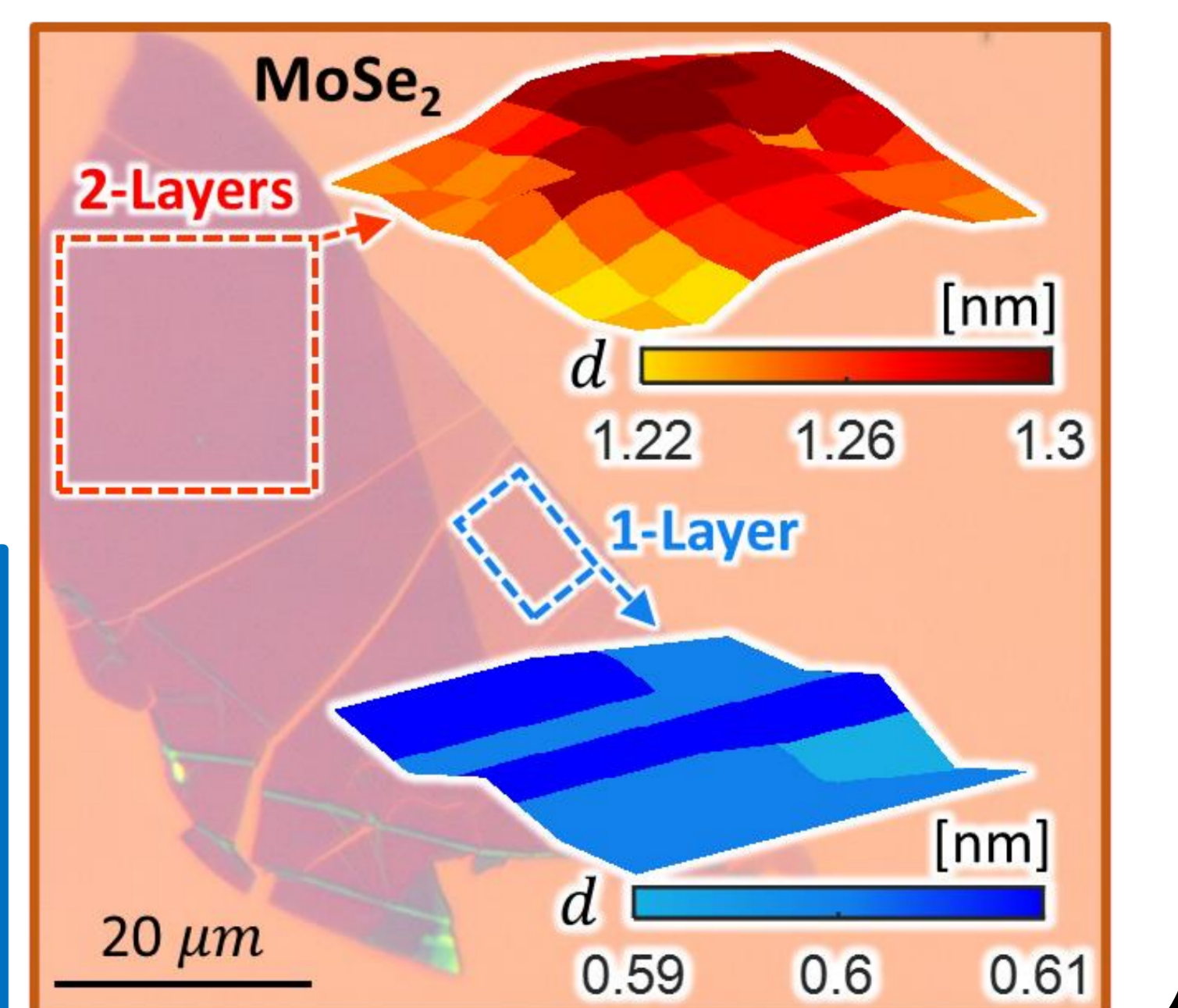
1L, 2L, 3L flakes of Graphene, hBN and TMDs



Thickness mapping on exfoliated MoSe₂ flake

SME instrumental accuracy: ± 0.005 nm

SME can accurately measure & map thicknesses of thin exfoliated 2D-materials



References

- R. Kenaz and R. Rapaport, United States Patent No. 11,262,293 B2, 2022.
- R. Kenaz and R. Rapaport, arXiv:2207.14161, 2022.
- R. Kenaz et al., arXiv:2211.07437, 2022.